

<b>Notice of References Cited</b>	Application/Control No. 10/720,444	Applicant(s)/Patent Under Reexamination TAKAHASHI ET AL.	
	Examiner Paul D Kim	Art Unit 3729	Page 1 of 1

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	N	JP 11083798 A	03-1999	Japan	NAKAMURA et al.	G01N 27/447
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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